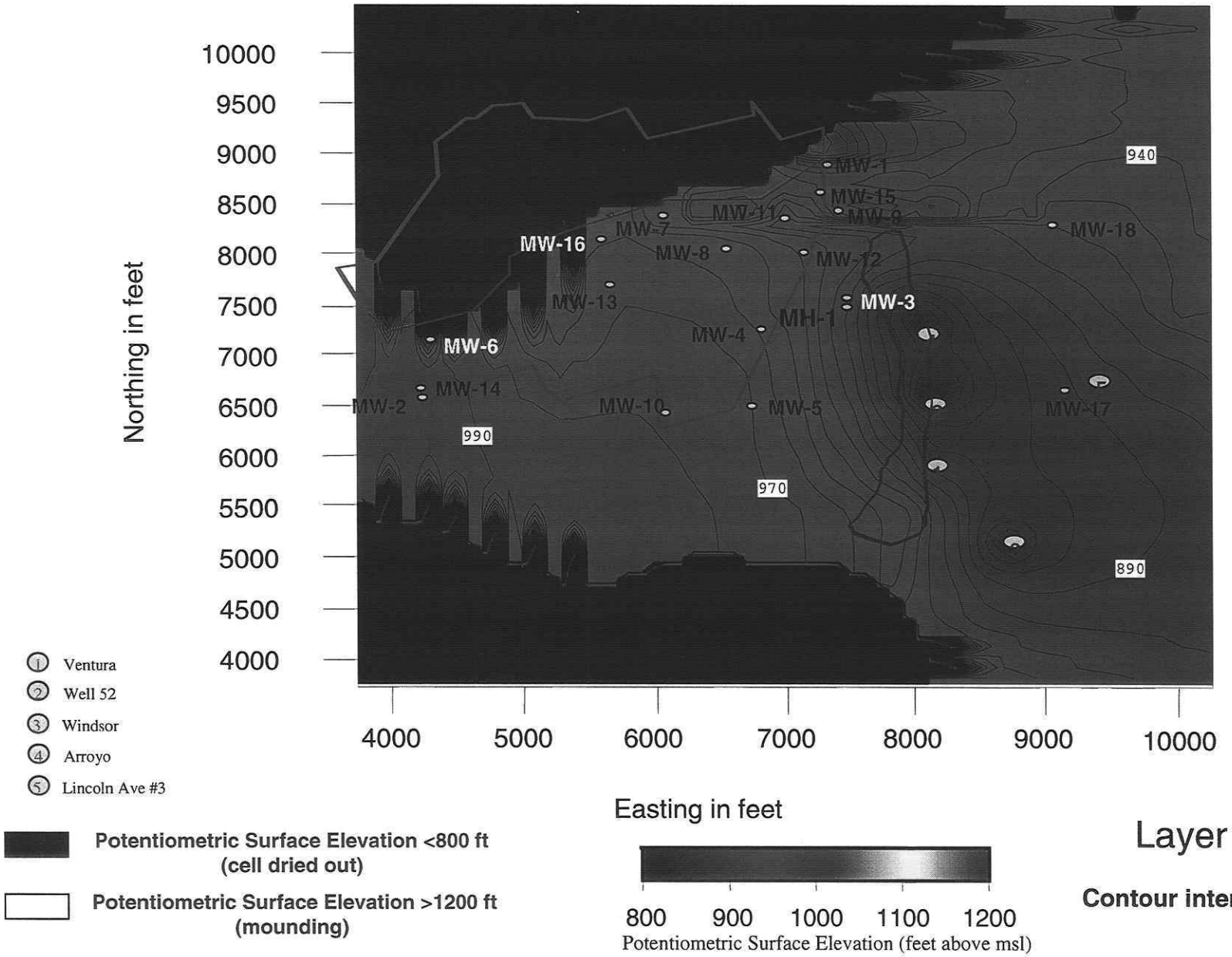

Figure 6-9c Simulated Piezometric Levels for Stress Period 2, Layer 3: October 1, 1995

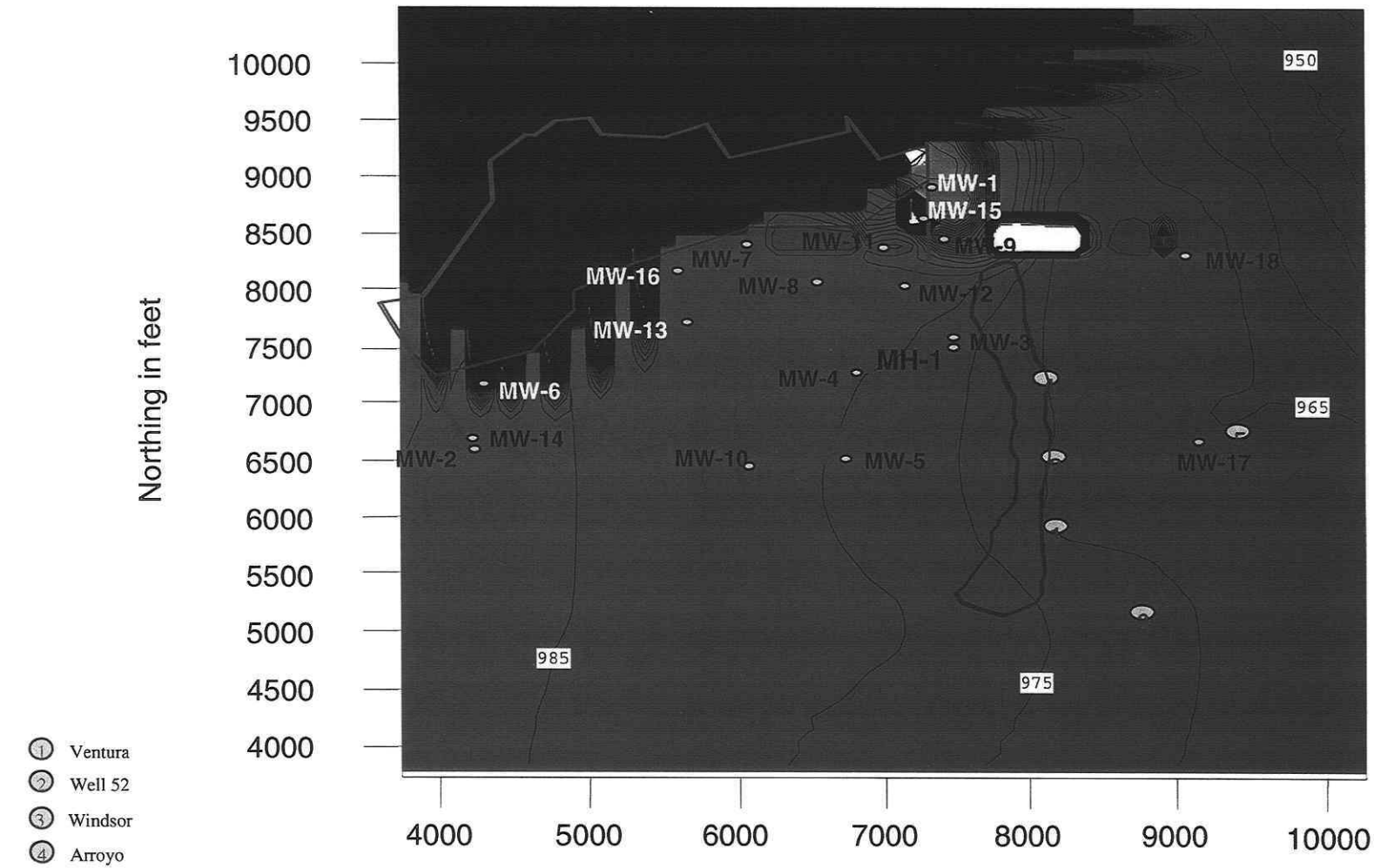

Figure 6-10a Simulated Piezometric Levels for Stress Period 3, Layer 1: November 1, 1995

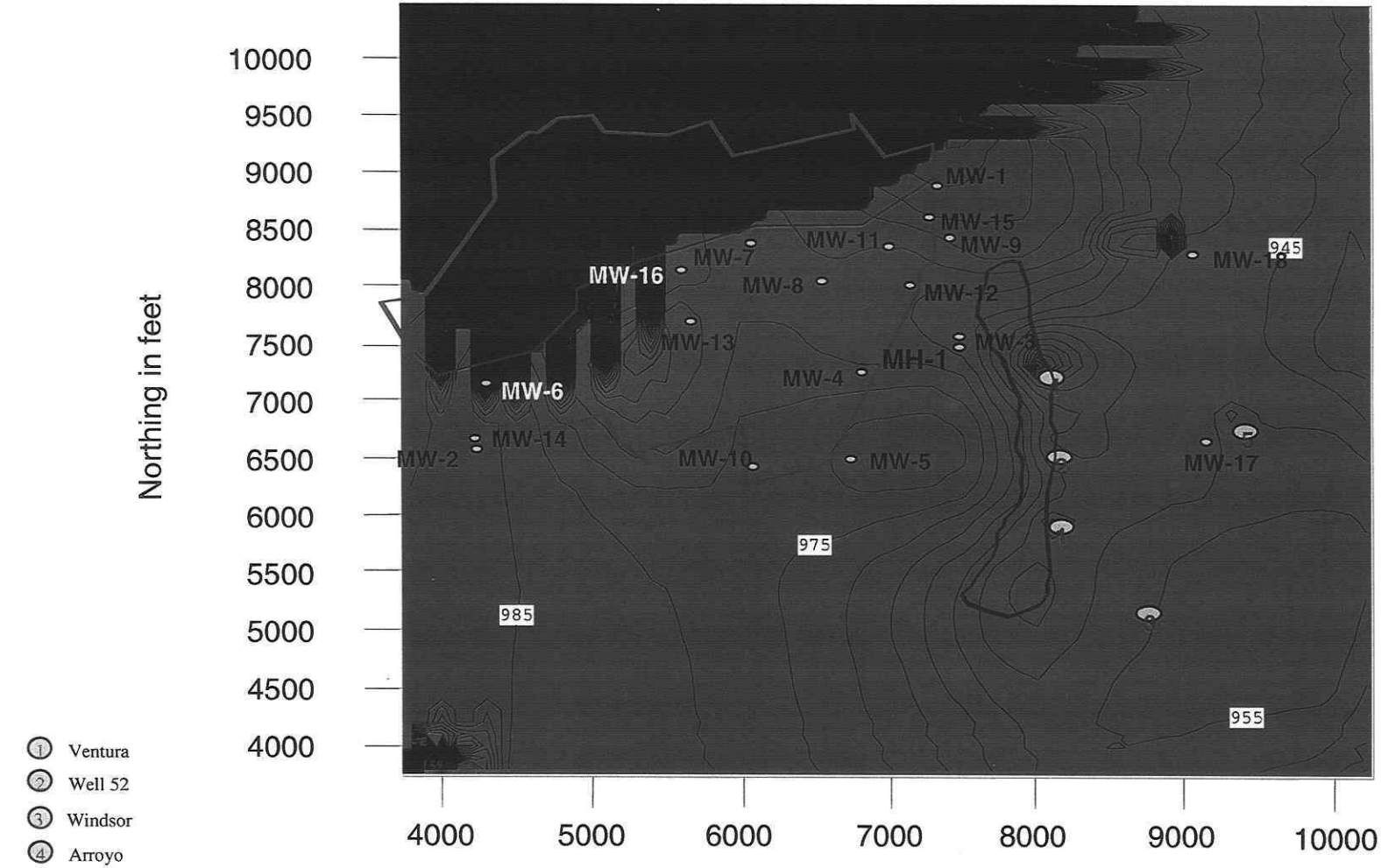

Figure 6-10b Simulated Piezometric Levels for Stress Period 3, Layer 2: November 1, 1995

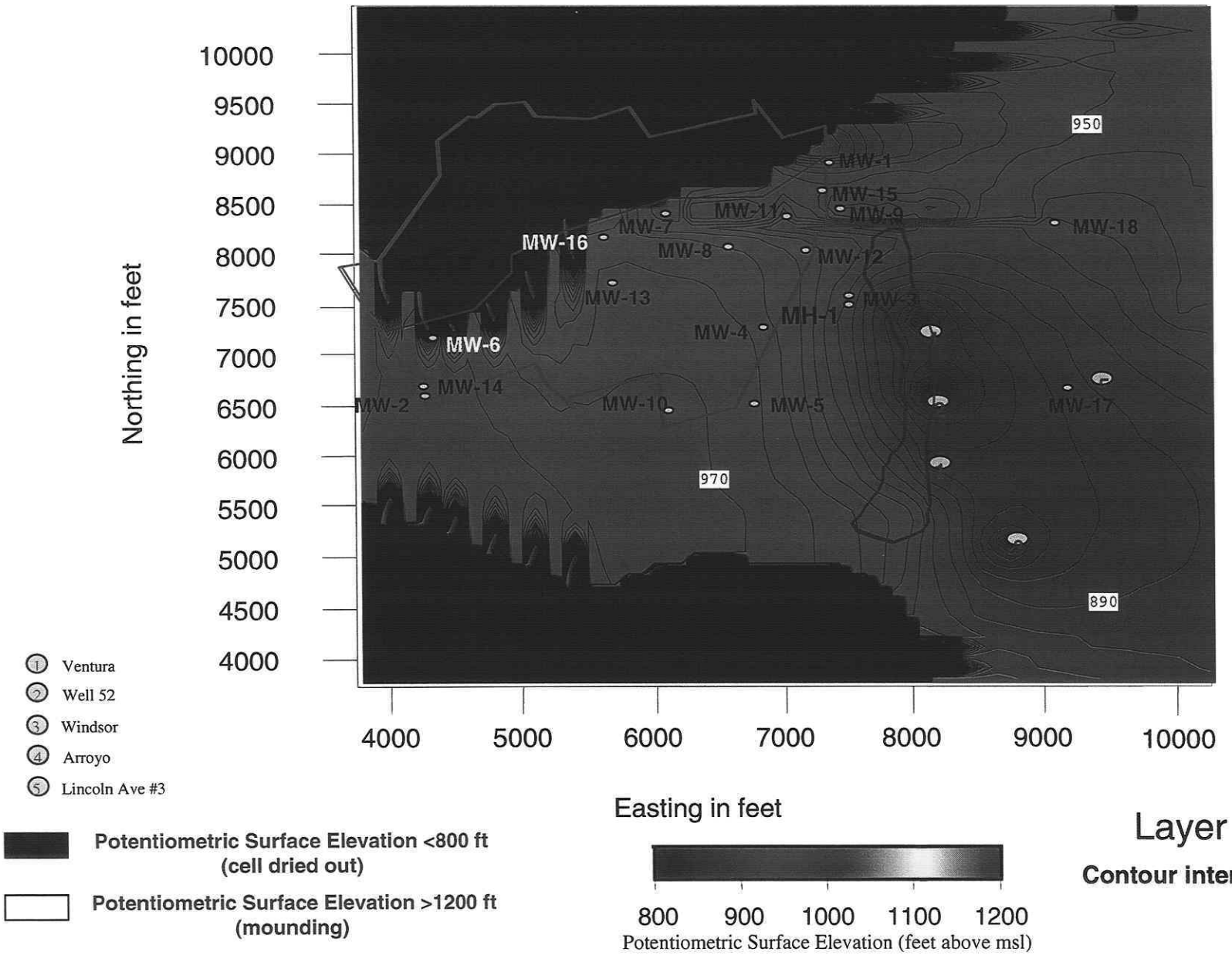

Figure 6-10c Simulated Piezometric Levels for Stress Period 3, Layer 3: November 1, 1995

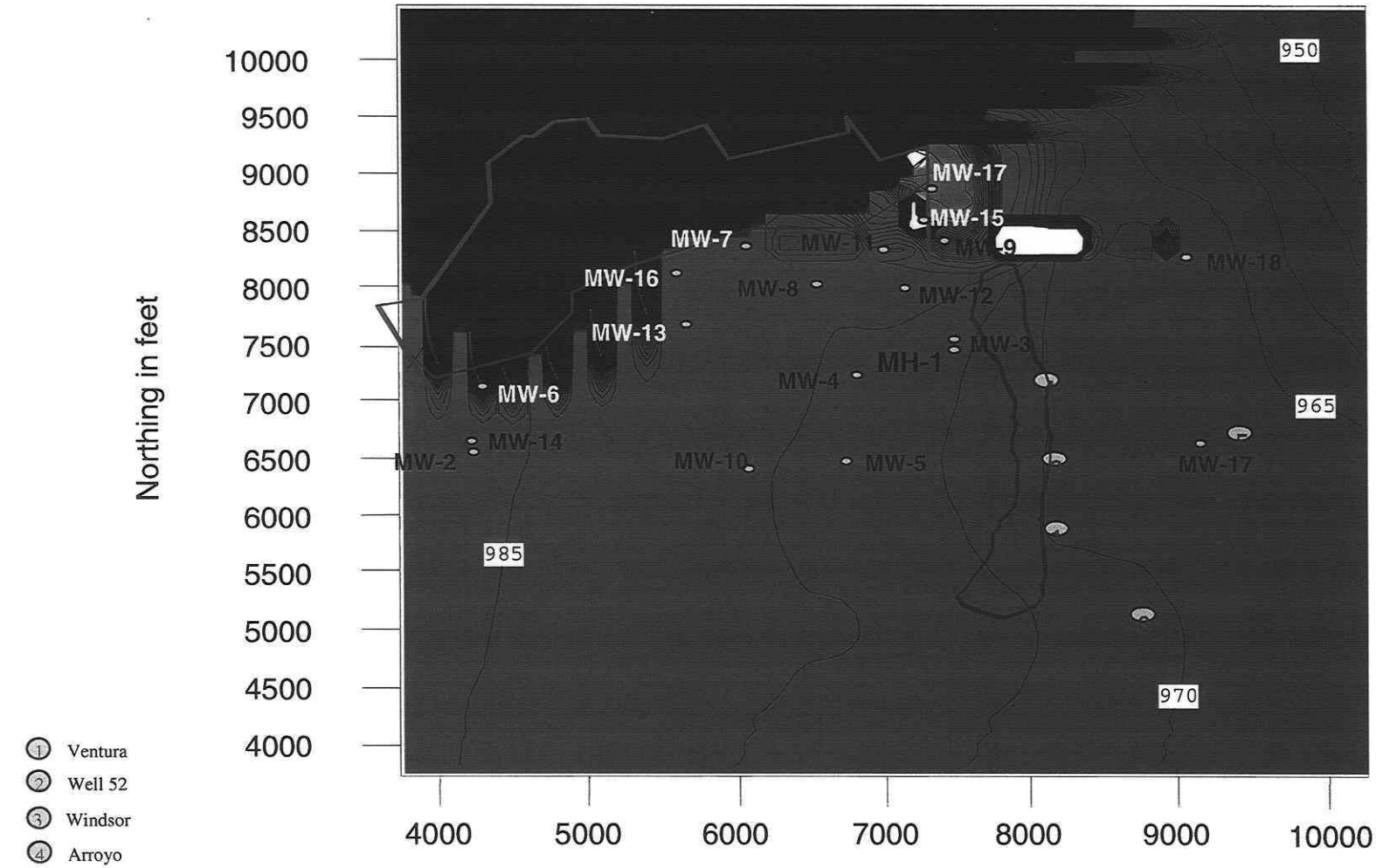

Figure 6-11a Simulated Piezometric Levels for Stress Period 4, Layer 1: December 1, 1995

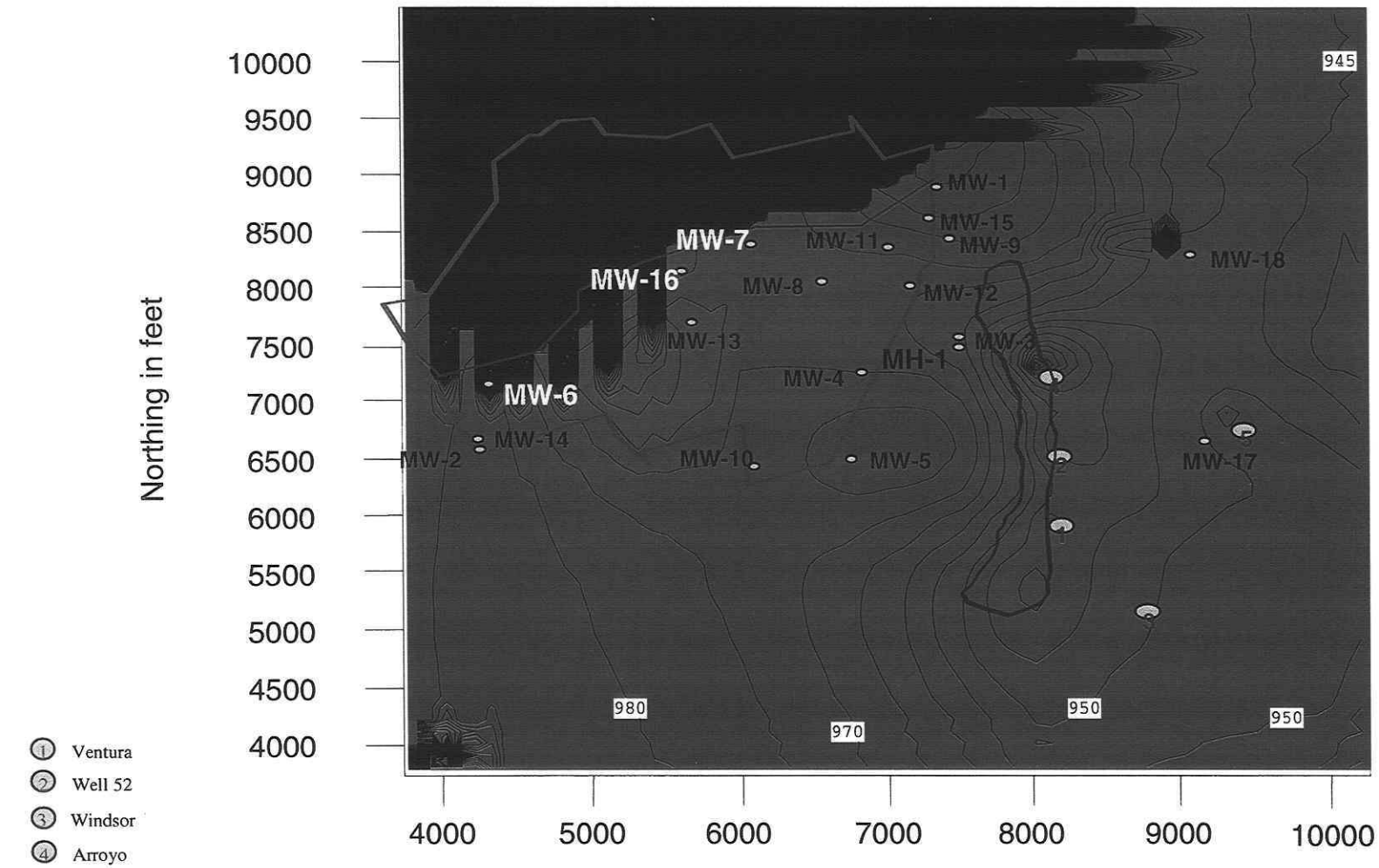

Figure 6-11b Simulated Piezometric Levels for Stress Period 4, Layer 2: December 1, 1995

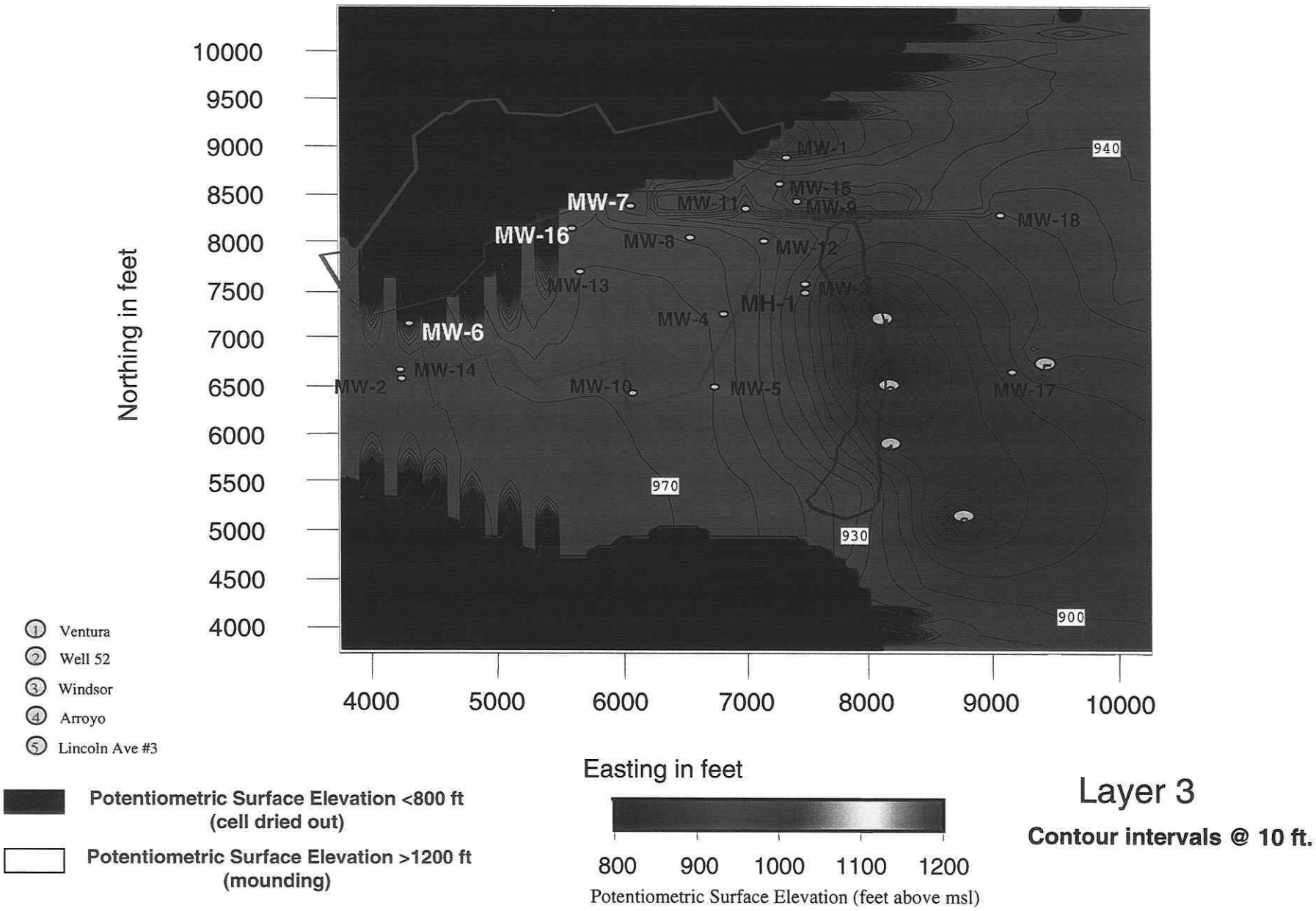

Figure 6-11c Simulated Piezometric Levels for Stress Period 4, Layer 3: December 1, 1995

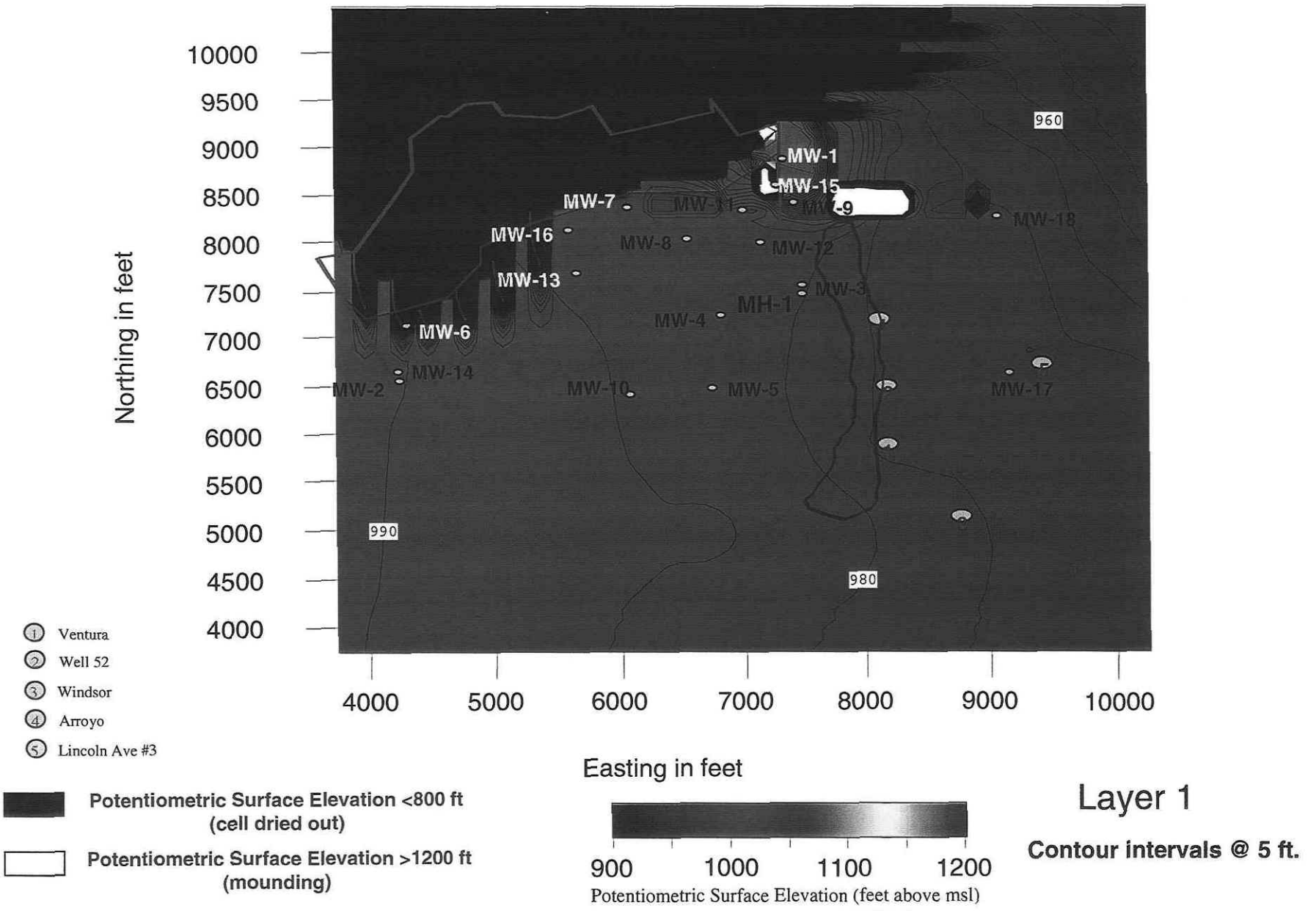

Figure 6-12a Simulated Piezometric Levels for Stress Period 5, Layer 1: January 1, 1996

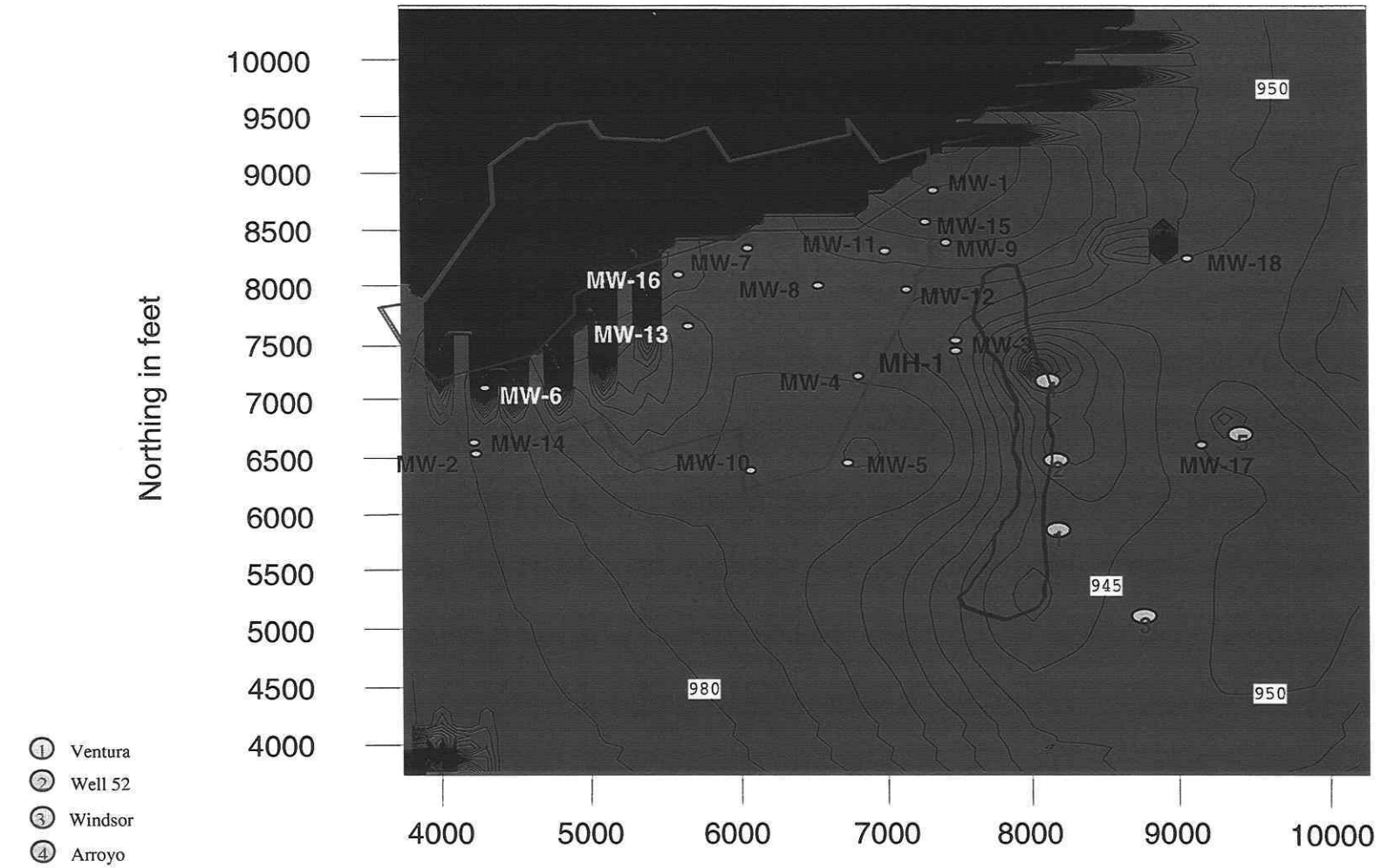

Figure 6-12b Simulated Piezometric Levels for Stress Period 5, Layer 2: January 1, 1996

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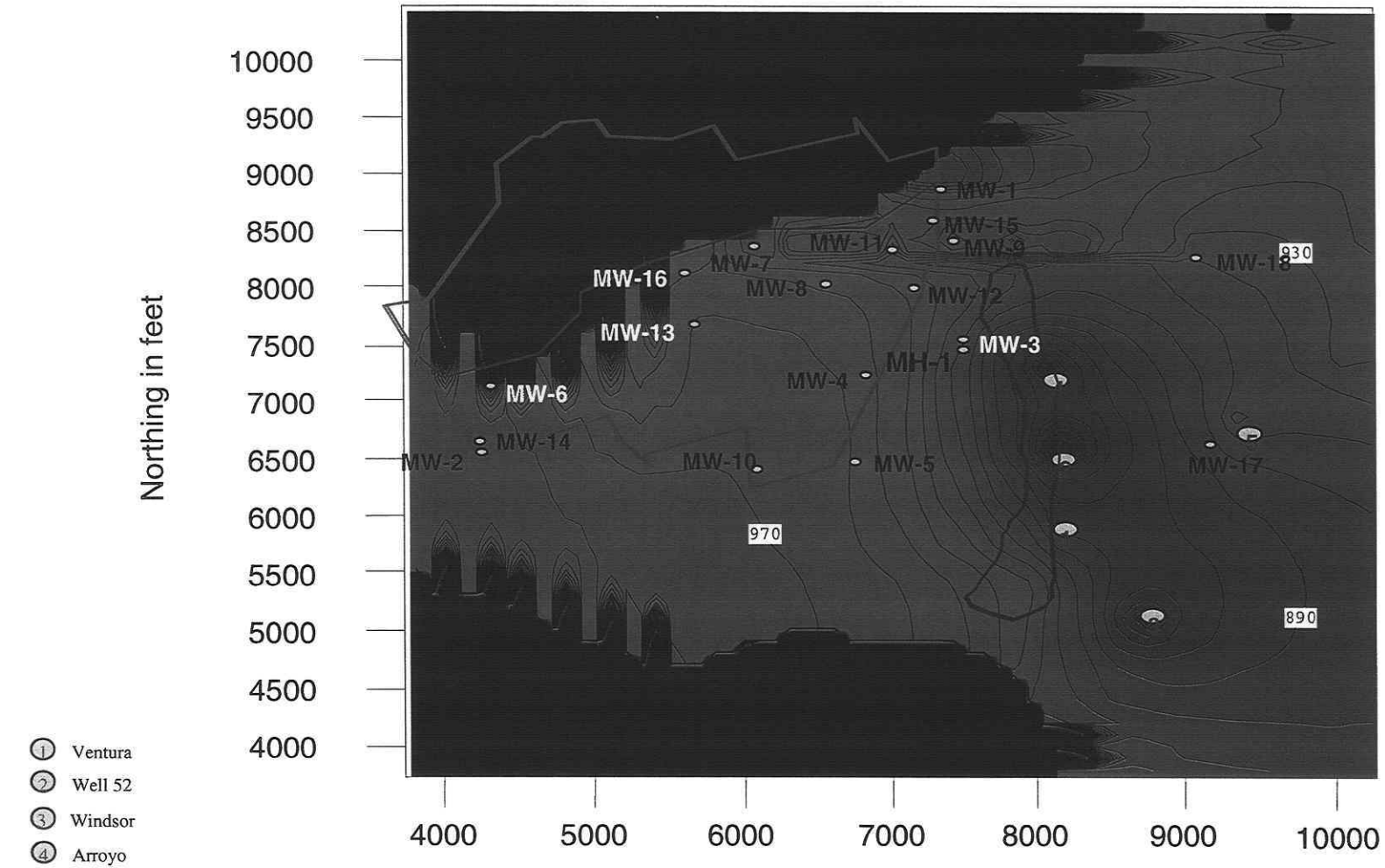

Figure 6-12c Simulated Piezometric Levels for Stress Period 5, Layer 3: January 1, 1996

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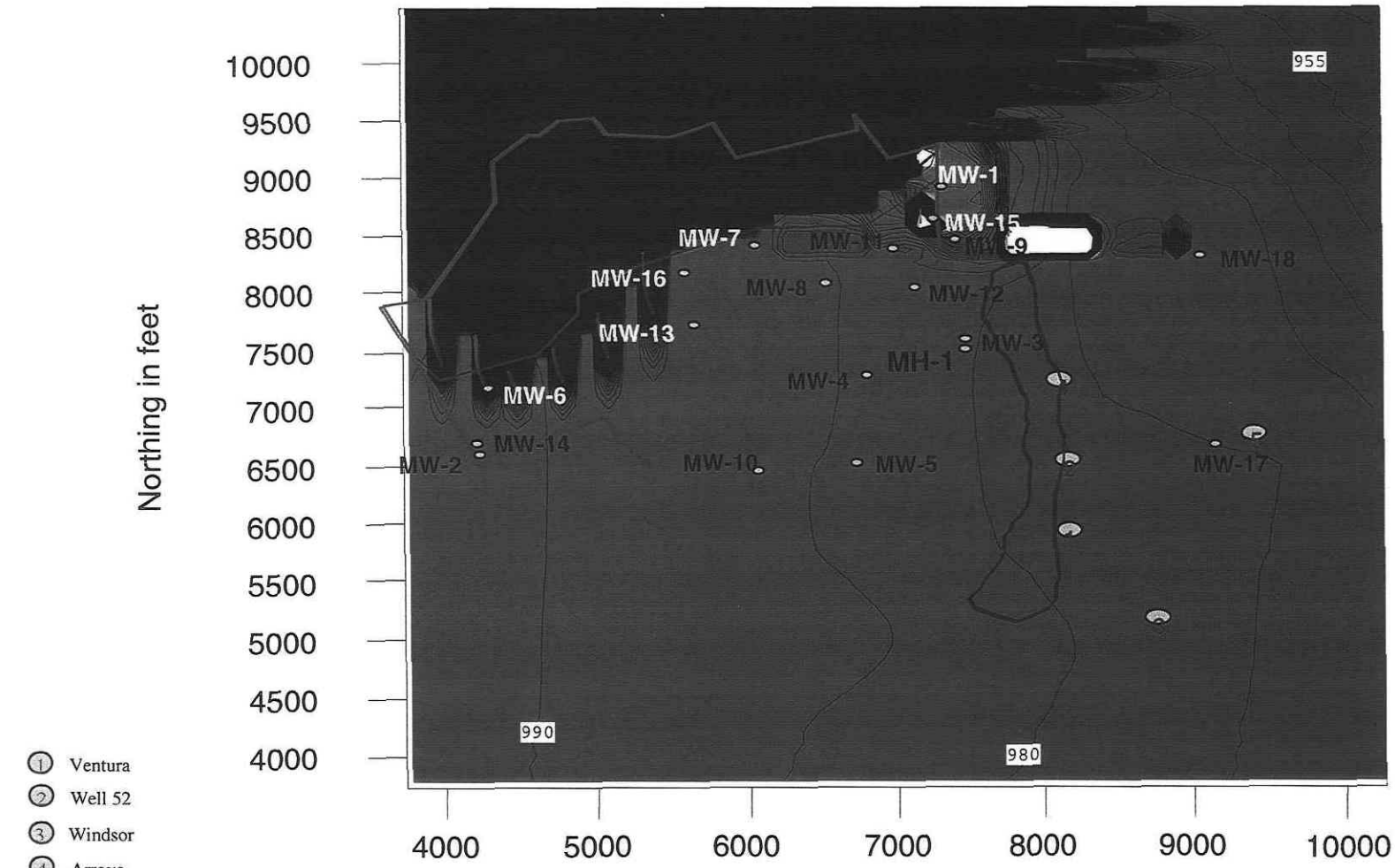


① Ventura
② Well 52
③ Windsor
④ Arroyo
⑤ Lincoln Ave #3

Potentiometric Surface Elevation <800 ft (cell dried out)

Potentiometric Surface Elevation >1200 ft (mounding)

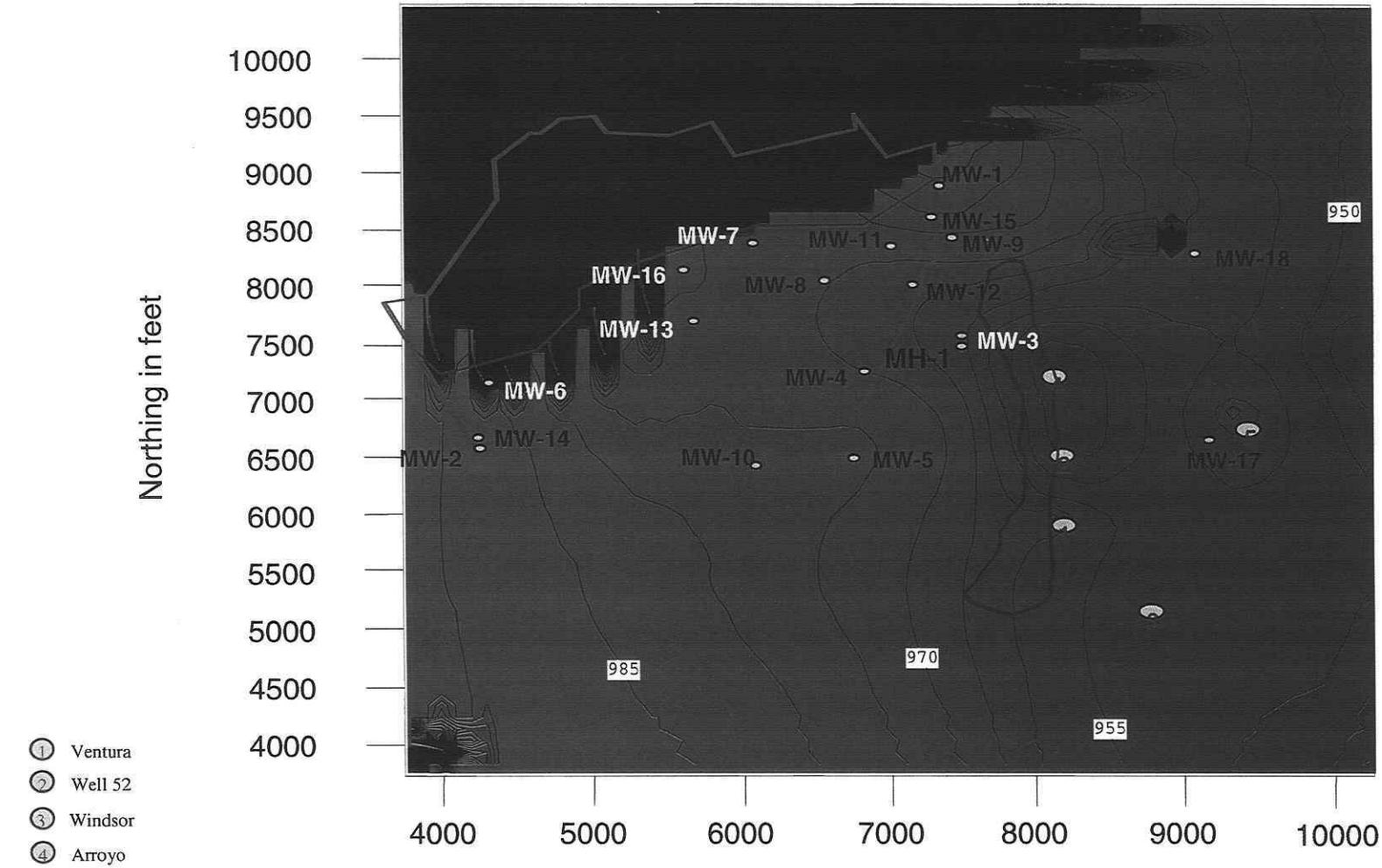
900 1000 1100 1200

Potentiometric Surface Elevation (feet above msl)

Layer 1

Contour intervals @ 5 ft.

Figure 6-13a Simulated Piezometric Levels for Stress Period 6, Layer 1: February 1, 1996



① Ventura
② Well 52
③ Windsor
④ Arroyo
⑤ Lincoln Ave #3

Potentiometric Surface Elevation <800 ft (cell dried out)

Potentiometric Surface Elevation >1200 ft (mounding)

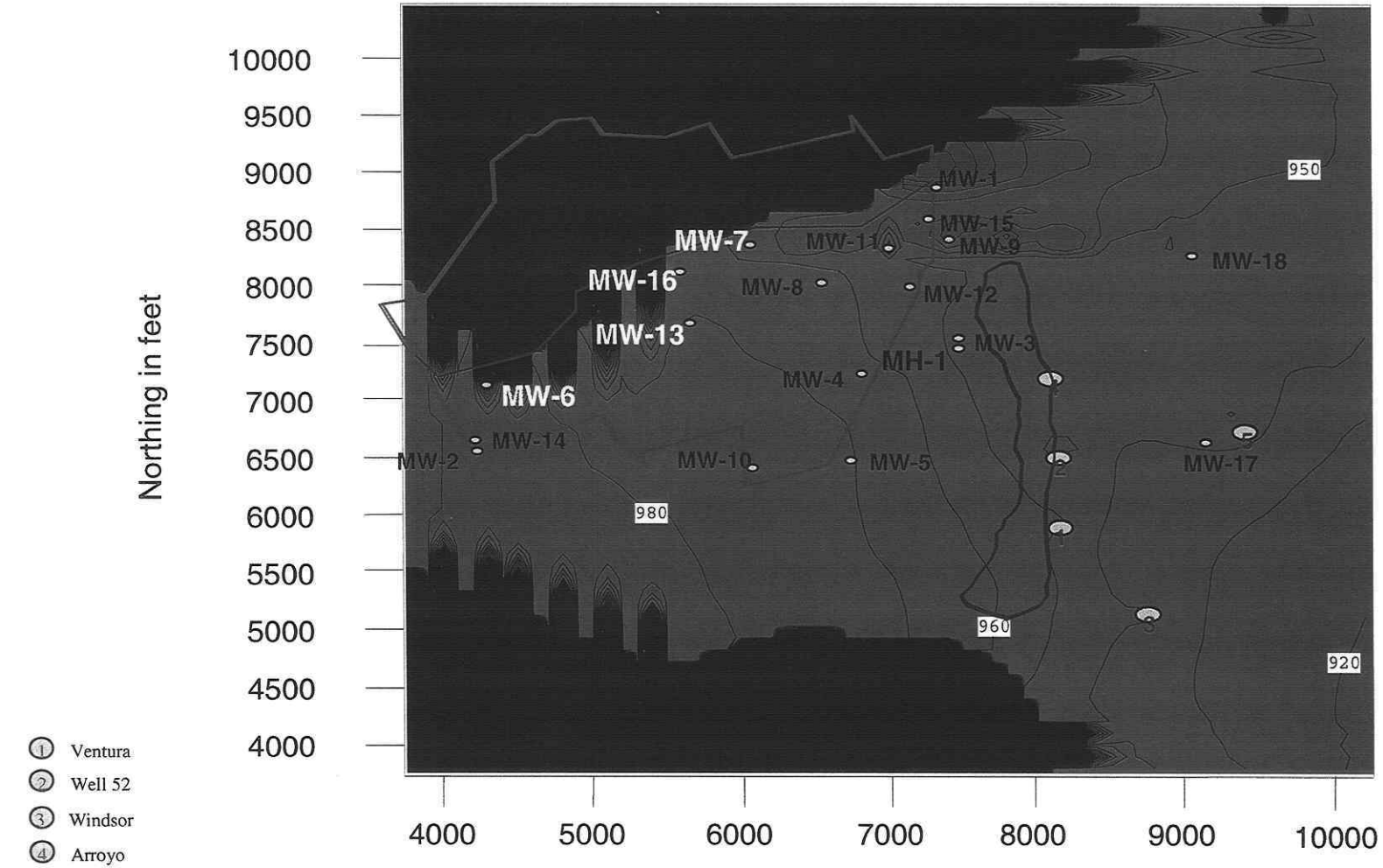
900 1000 1100 1200

Potentiometric Surface Elevation (feet above msl)

Layer 2

Contour intervals @ 5 ft.

Figure 6-13b Simulated Piezometric Levels for Stress Period 6, Layer 2: February 1, 1996



① Ventura
② Well 52
③ Windsor
④ Arroyo
⑤ Lincoln Ave #3

Potentiometric Surface Elevation <800 ft (cell dried out)

Potentiometric Surface Elevation >1200 ft (mounding)

800 900 1000 1100 1200

Potentiometric Surface Elevation (feet above msl)

Layer 3

Contour intervals @ 10 ft.

Figure 6-13c Simulated Piezometric Levels for Stress Period 6, Layer 3: February 1, 1996

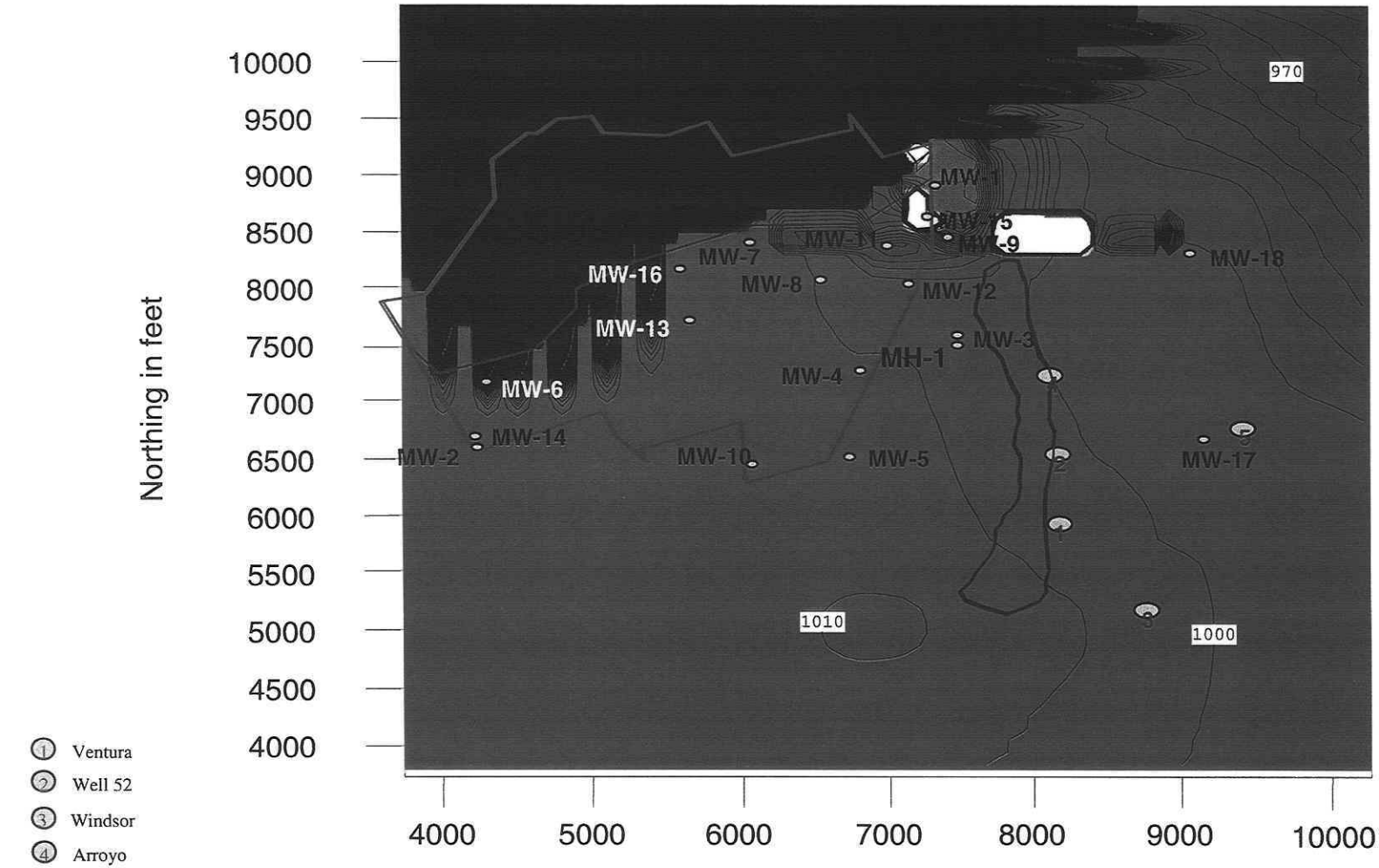


Figure 6-14a Simulated Piezometric Levels for Stress Period 7, Layer 1: March 1, 1996

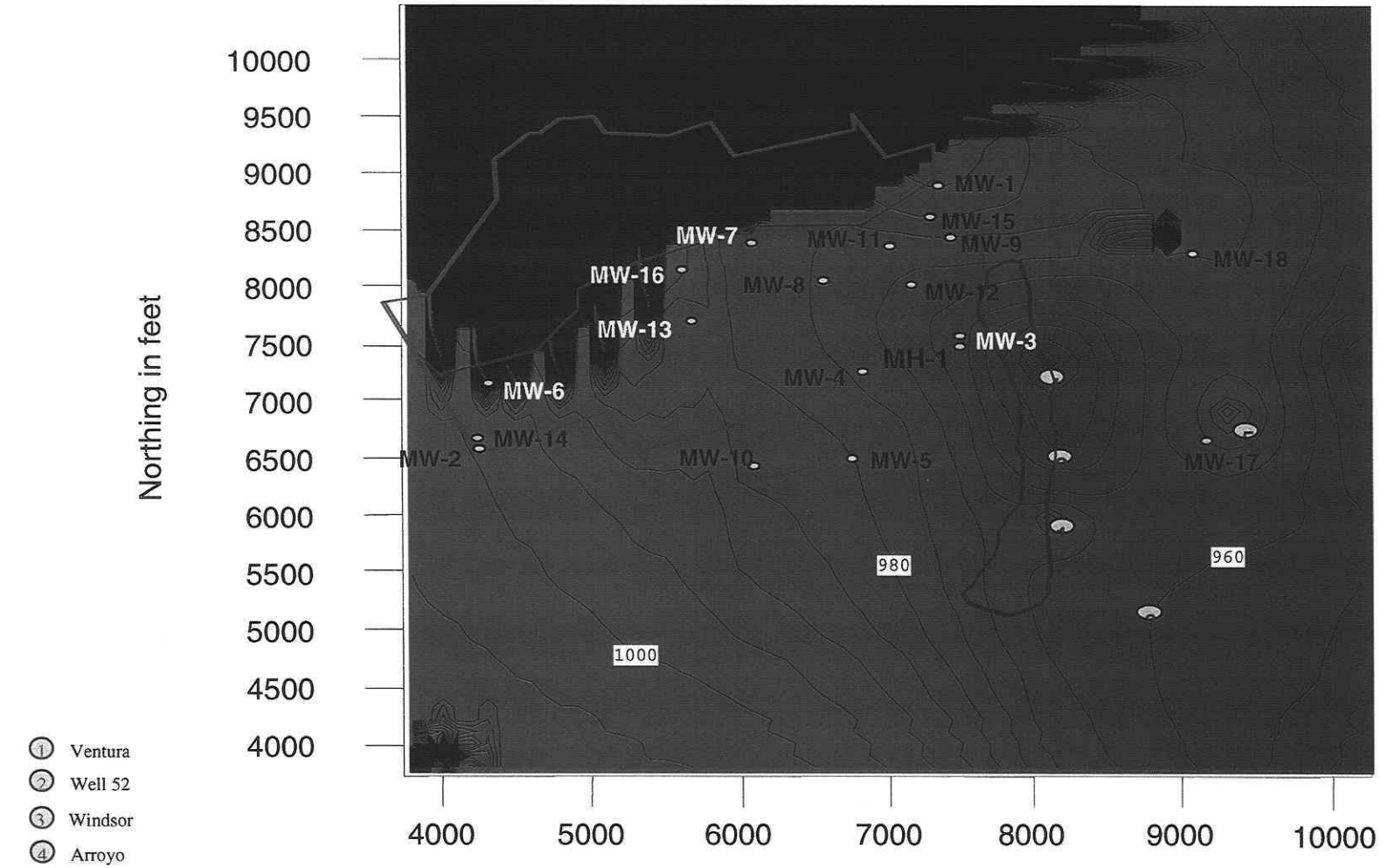


Figure 6-14b Simulated Piezometric Levels for Stress Period 7, Layer 2: March 1, 1996

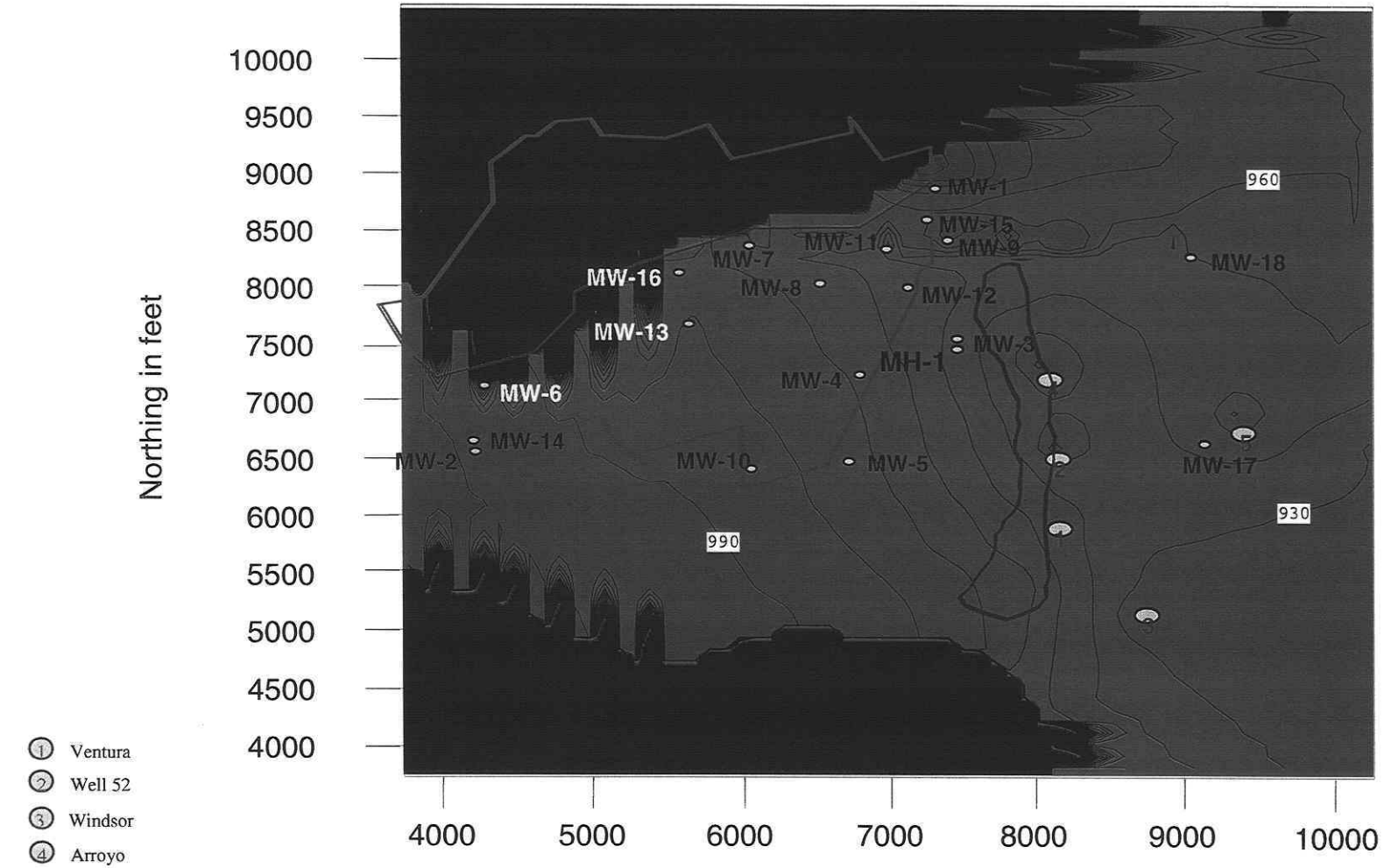


Figure 6-14c Simulated Piezometric Levels for Stress Period 7, Layer 3: March 1, 1996

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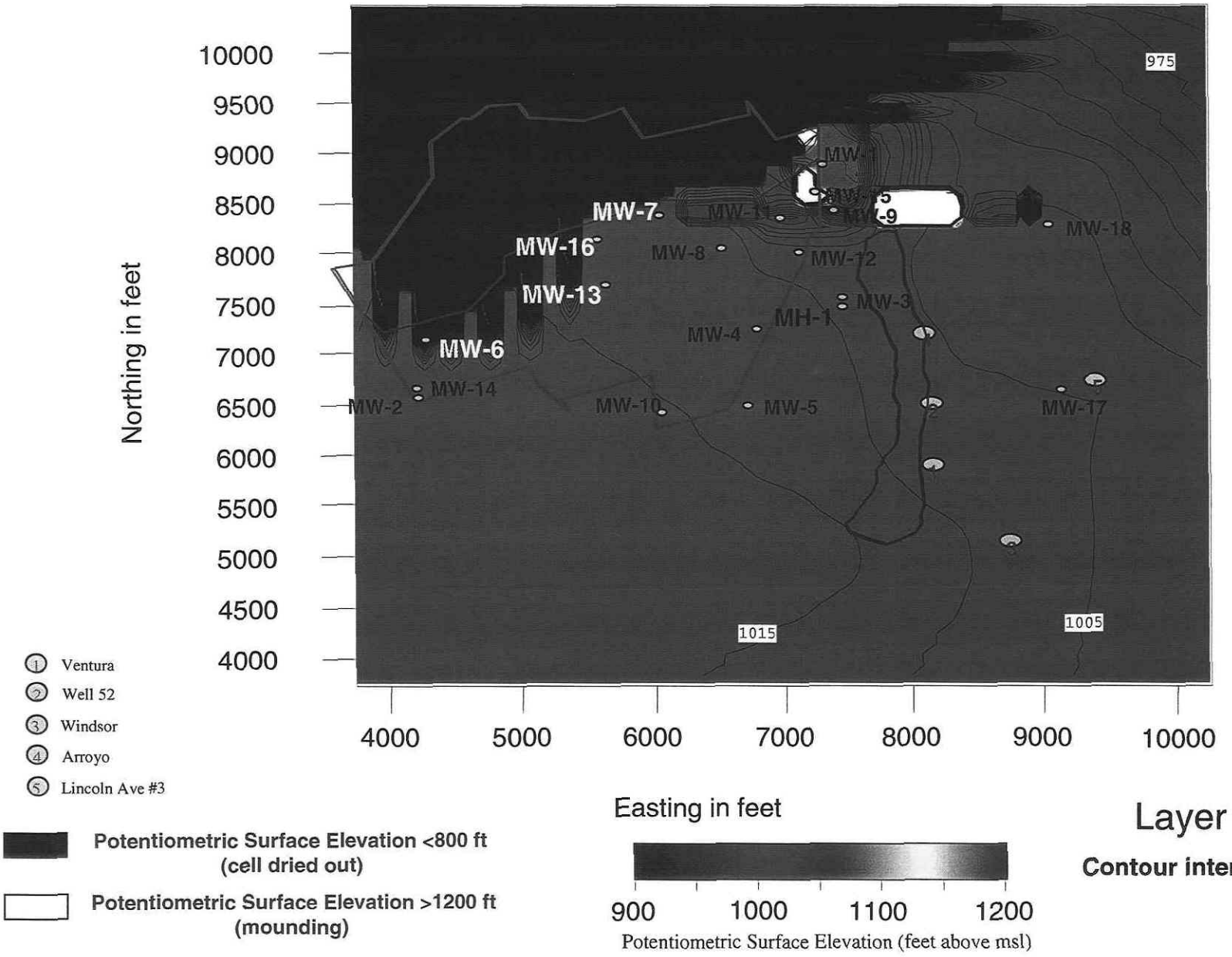

Figure 6-15a Simulated Piezometric Levels for Stress Period 8, Layer 1: April 1, 1996

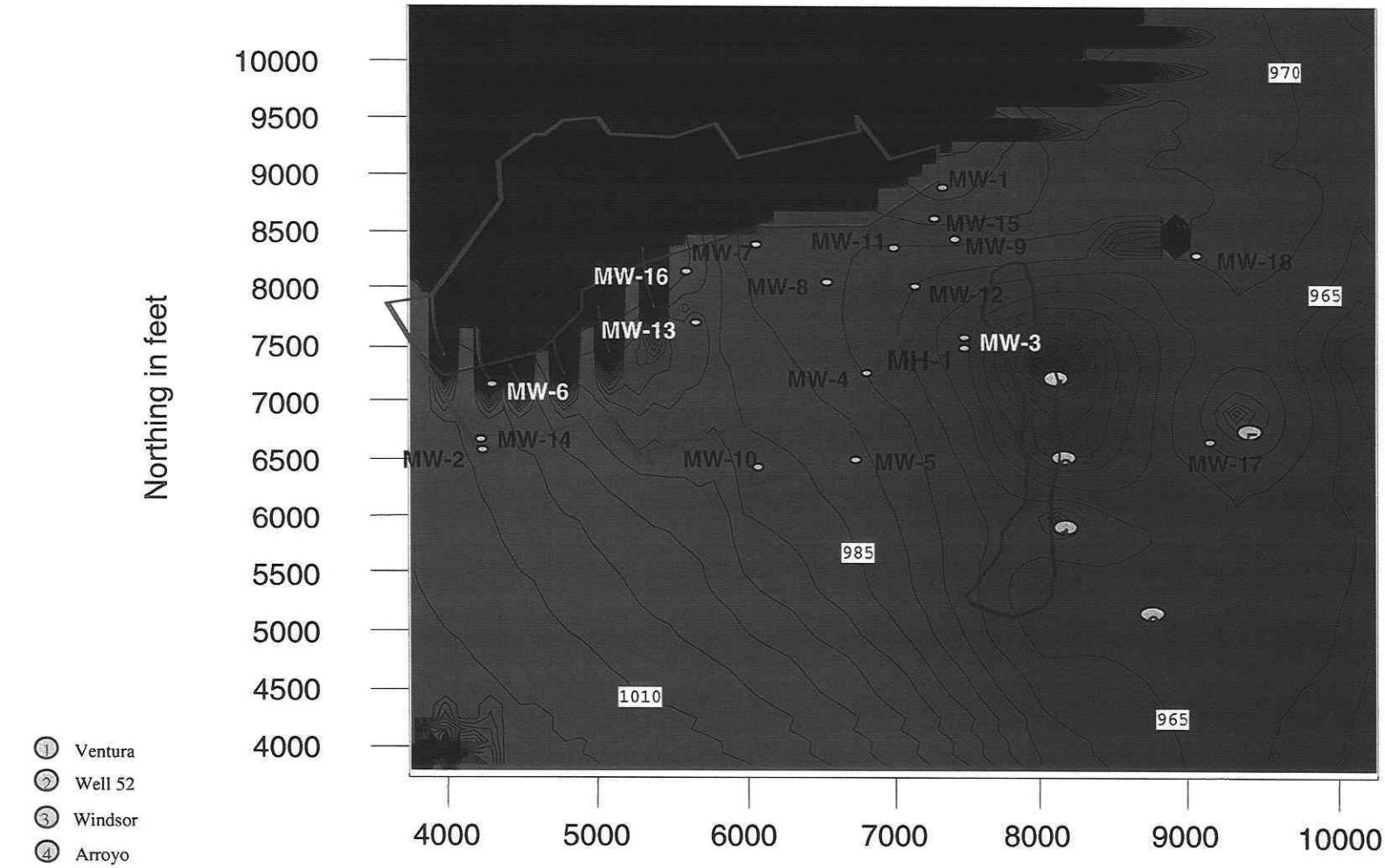

Figure 6-15b Simulated Piezometric Levels for Stress Period 8, Layer 2: April 1, 1996

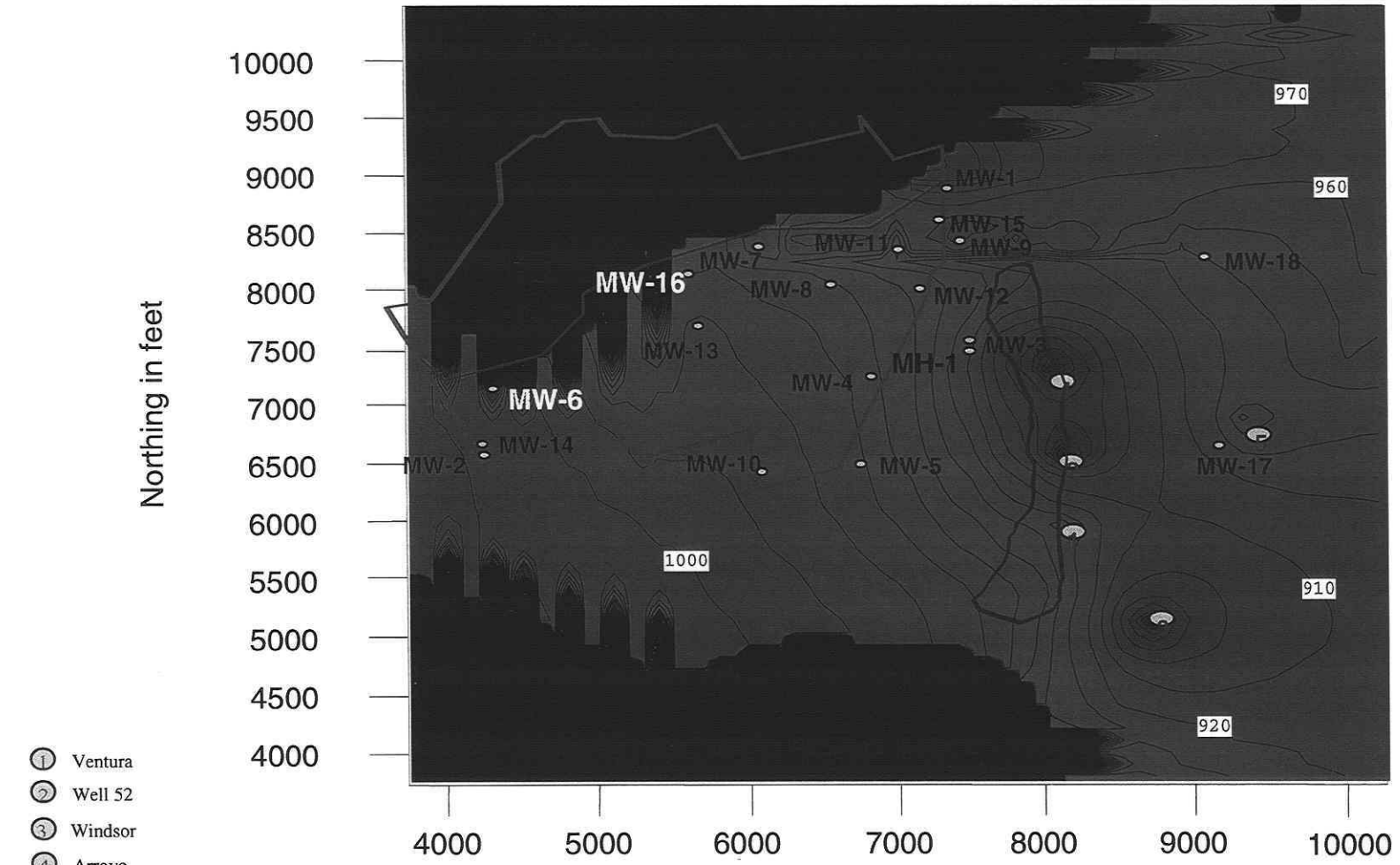

Figure 6-15c Simulated Piezometric Levels for Stress Period 8, Layer 3: April 1, 1996